t k.	Application No.	Applicant(s)
Notice of Allowability	10/090,413	TAMATA ET AL.
	Examiner	Art Unit
	Igor N. Borissov	3628
The MAILING DATE of this communication apperature All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIOF of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED i or other appropriate comm IGHTS. This application is	n this application. If not included unication will be mailed in due course. THIS
1. X This communication is responsive to Request for Continue	d Examination (RCE) OF 0	<u>4/30/2007</u> .
2. 🔀 The allowed claim(s) is/are <u>1-21</u> .		
 Acknowledgment is made of a claim for foreign priority ur a)	e been received. e been received in Application cuments have been received of this communication to file IENT of this application.	on No d in this national stage application from the e a reply complying with the requirements
INFORMAL PATENT APPLICATION (PTO-152) which give		
5. CORRECTED DRAWINGS (as "replacement sheets") mus	st be submitted.	
(a) ☐ including changes required by the Notice of Draftspers	on's Patent Drawing Review	w (PTO-948) attached
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date		
(b) ☐ including changes required by the attached Examiner's Paper No./Mail Date		
Identifying indicia such as the application number (see 37 CFR 1 each sheet. Replacement sheet(s) should be labeled as such in the		
 DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT 		
Attachment(s)	- -	
1. Notice of References Cited (PTO-892)		formal Patent Application
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	Paper No.	ummary (PTO-413), /Mail Date
 Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date 	7. 🛭 Examiner's	Amendment/Comment
4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material	8. ⊠ Examiner's 9. ☐ Other	Statement of Reasons for Allowance
		IGOR N. BORISSOV PRIMARY EXAMINER

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DETAILED ACTION

Continued Examination Under 37 CFR 1.114

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 4/30/2007 has been entered.

Response to Amendment

Amendment received on 4/30/2007 is acknowledged and entered. Claims 1-6, 8-14, 16-20 have been amended. New claim 21 has been added. Claims 1-21 are currently pending in the application.

Claim Rejections under 35 USC § 112 and 35 USC § 103 have been withdrawn due to the applicant's amendment.

EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

The application has been amended as follows:

IN THE CLAIMS

 (Currently amended) A process for treating perfluoride released from a manufacturer's plant by perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising: Application/Control Number: 10/090,413 Page 3

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installing the perfluoride treating apparatus owned by the independent separate perfluoride[[,]] treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant[[;]], the perfluoride treating apparatus owned by the independent separate perfluoride treatment service provider;

using the perfluoride treating apparatus to treat perfluoride released from the manufacturer's plant;

recording information generated by the perfluoride treatment;

calculating a cost and an amount of the perfluoride treatment based on the recorded information;

billing the manufacturer the calculated cost.

2. (Currently amended) A process for treating perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising:

installing the perfluoride treating apparatus ewned-by the <u>independent separate</u> perfluoride treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant[[;]], the perfluoride treating apparatus owned by the independent separate perfluoride treatment service provider;

using the perfluoride treating apparatus to treat perfluoride released from the manufacturer's plant;

recording information generated by the perfluoride treatment;

calculating a cost and an amount of the perfluoride treatment base<u>d</u> on the recorded information, wherein the cost is transmitted to a server of the <u>independent</u> separate perfluoride treatment service provider via a network;

billing the manufacturer the calculated cost.

3. (Currently amended) The process according to Claim 1, <u>wherein</u> the recorded information is transmitted via communication circuits and indicated on a display device.

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4. (Currently amended) The process according to Claim 1, wherein [[the]] the recorded information includes a flow rate of exhaust gas from the manufacturer's plant.

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- 5. (Currently amended) The process according to Claim 1, wherein the recorded information includes [[on]] a flow rate of PFC gas supplied to the manufacturer's plant.
- 6. (Currently amended) The process according to Claim 1, wherein the recorded information includes a number of sheets of <u>at least one of either</u> blank material supplied to the manufacturer's plant [[or]] <u>and</u> material taken out from the manufacturer's plant.
- 7. (Original) The process according to Claim 6, wherein the blank material is wafer.
- 8. (Currently amended) The process according to Claim 1, wherein the manufacturer's plant is a semiconductor manufacturing plant, and the recorded information includes an amount of perfluoride required for working wafers in the manufacturer's plant.
- 9. (Currently amended) The process according to Claim 1, wherein the manufacturer's plant is <u>at least one of either</u> a semiconductor manufacturing plant [[or]] and a liquid crystal producing plant.
- 10. (Currently amended) A system for treating perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising:

means of treating perfluoride connected to the manufacturer's plant[[;]] by the independent separate perfluoride treatment service provider;

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means for estimating a decomposition treated amount of perfluoride contained in exhaust gas from a manufacturer's plant based on data of an operation of the manufacturer's plant,

wherein the data of the operation are transmitted by a communication means to a [[a]] the <u>independent separate</u> perfluoride treatment service provider;

means for calculating a cost of treatment of the perfluoride based on an estimated amount of the perfluoride treated; and

means of billing the manufacturer.

- 11. (Currently amended) The process according to Claim 2, wherein the recorded information is transmitted via communication circuits and indicated on a display device.
- 12. (Currently amended) The process according to Claim 2, <u>wherein</u> the recorded information includes a flow rate of exhaust gas from the manufacturer's plant.
- 13. (Currently amended) The process according to Claim 2, <u>wherein</u> the recorded information includes a flow rate of PFC gas supplied to the manufacturer's plant.
- 14. (Currently amended) The process according to Claim 2, wherein the recorded information includes a number of sheets of <u>at least one of either</u> blank material supplied to the manufacturer's plant [[or]] and material taken out from the manufacturer's plant.
- 15. (Original) The process according to Claim 14, wherein the blank material is wafer.
- 16. (Currently amended) The process according to Claim 2, wherein the manufacturer's plant is a semiconductor manufacturing plant, and the recorded information includes an amount of perfluoride required for working wafers in the semiconductor manufacturing plant.

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17. (Currently amended) The process according to Claim 2, wherein the manufacturer's plant is <u>at least one of either</u> a semiconductor manufacturing plant [[or]] <u>and</u> a liquid crystal producing plant.

18. (Currently amended) A process system for treating perfluoride released from a manufacturer's plant by a perfluoride treating apparatus owned and provided by an independent separate perfluoride treatment service provider, comprising:

the perfluoride treatment apparatus connected to the manufacturer's plant[[;]] <u>by</u> the independent separate perfluoride treatment service provider;

a first computer configured to estimate a treated amount of perfluoride contained in exhaust gas from the manufacturer's plant based on a data of an operation of the manufacturer's plant, wherein the data of the operation [[are]] is transmitted by a communications network to [[an]] the independent separate perfluoride treatment service provider[[,]]; and[[;]]

a second computer configured to calculate a cost of treatment of the perfluoride based on the estimated amount of the perfluoride treated.

- 19. (Currently amended) The process <u>system</u> according to claim 18, wherein the first computer is a part of a decomposition treating apparatus.
- 20. (Currently amended) The process <u>system</u> according to claim 18 wherein the second computer includes an information terminal and <u>means for connecting to</u> the <u>communications network in the Internet.</u>

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Allowable Subject Matter

Claims 1-21are allowed.

The following is an examiner's statement of reasons for allowance:

As per independent claims 1, 2 and 10, the best prior art, Arno in view of Faeth, teaches a method and system for treating perfluorides generated during semiconductor manufacturing (by treatment undertaker); considering factors which can increase or decrease a cost of said treatment of said perfluorides; calculating a cost of said treatment of said perfluorides, wherein information regarding the amount of pollutants treated is transmitted to a server, and wherein the server receives the information of an amount of pollutants treated from a plurality of pollutants generated entities.

However, Arno in view of Faeth fails to teach or fairly suggest installing the perfluoride treating apparatus by an independent separate perfluoride treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant, wherein said perfluoride treating apparatus owned by said independent separate perfluoride treatment service provider.

The best foreign art, Mori et al. (EP 1 129 775 A1), while teaching a method and system of decomposing a fluorine-containing compound in manufacturing environment, fails to teach or fairly suggest installing the perfluoride treating apparatus by an independent separate perfluoride treatment service provider at the manufacturer's plant, and connecting the perfluoride treating apparatus to the manufacturer's plant, wherein said perfluoride treating apparatus owned by said independent separate perfluoride treatment service provider.

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The remaining dependent claims are considered allowable, as they are dependent and based of an allowable independent claims.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submission should be clearly labeled "Comments on Statement of Reason for Allowance".

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Igor Borissov whose telephone number is 571-272-6801. If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, John W. Hayes can be reached on 571-272-6708. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

IB

07/07/2007

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